Special Issue

MEMS Devices for Nanomanufacturing

Message from the Guest Editors

Dear colleagues, High-volume nanomanufacturing is a key technology driver crucial for the development of novel, high-performance, and low-cost miniaturized products with applications in several industries. However, materials development and quality control of production in nanoscale have been two of the most difficult challenges. Developing materials for nanoscale applications requires higher precision in the placement and manipulation of the material. In addition, nanomaterial requires a more detailed analysis to find defects and to perform quality control. These challenges can be effectively addressed with the development of application-specific MEMS and NEMS devices to fulfill the requirements of precision, scalability, process control, and metrology. For this Special Issue, we invite you to contribute to the design, development, production, and testing of nanomaterials using MEMS devices for nanomanufacturing. This special issue will cover the spectrum of the nanomanufacturing process flow from start to end, manufacturing process design, novel production methods, nanomaterial testing using MEMS devices.

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